

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the applications:

Listing of Claims:

Claims 1-39 (Canceled)

40. (Currently amended): ~~An apparatus~~ workpiece deposition system for replaceably preventing deposition on a portion of ~~the~~ a workpiece in a processing system comprising:

~~a) a deposition chamber for depositing a film on a workpiece;~~

a) b) a workpiece support positioned within the deposition chamber processing system for supporting the workpiece; and

b) e) a replaceable shield of comparable weight as the workpiece, the shield engaging a portion of the workpiece on the opposite side of the workpiece support and shielding the engaged portion of the workpiece during deposition thereof to prevent deposition on the engaged portion of the workpiece;

wherein the comparable weight of the replaceable shield and the workpiece allows replacement of the shield in the same way as the replacement of the workpiece[[,]].

41. (Currently amended): A workpiece deposition system for replaceably preventing deposition on a portion of ~~the~~ a workpiece comprising:

~~a) a deposition chamber for depositing a film on [[a]] the workpiece;~~

~~b) a workpiece replacement chamber in communication with the deposition chamber, the workpiece replacement chamber comprising a workpiece replacement system for replacing the workpiece from the deposition chamber;~~

b) e) a workpiece support positioned within the deposition chamber for supporting the workpiece; and

c) ~~d)~~ a replaceable shield of comparable weight as the workpiece, the shield engaging a portion of the workpiece on the opposite side of the workpiece support and shielding the engaged portion of the workpiece during deposition thereof to prevent deposition on the engaged portion of the workpiece;
wherein the comparable weight of the replaceable shield and the workpiece allows replacement of the shield in the same way as the replacement of the workpiece[[,]].

42. (Previously amended): An apparatus as in claim 41 further comprising a shield restraint clamp for holding the shield against the portion of the workpiece.
43. (Previously amended): An apparatus as in claim 42 further comprising a shield restraint press for pressing on the shield restraint clamp so that the shield is pressing against the portion of the workpiece.
44. (Previously amended): An apparatus as in claim 43 in which the shield restraint press employs a spring action for pressing on the shield restraint clamp.
45. (Previously amended): An apparatus as in claim 42 further comprising a shield restraint support for supporting the shield restraint clamp so that the shield and the shield restraint clamp are spaced apart when the workpiece is disengaged from the shield.
46. (Previously amended): An apparatus as in claim 41 further comprising a shield support for supporting the shield so that the shield and the workpiece are spaced apart when the workpiece is disengaged from the shield.
47. (Previously amended): An apparatus as in claim 46 further comprising a shield aligner connected to the shield and the shield support for aligning the shield with the shield support.

48. (Previously amended): An apparatus as in claim 41 further comprising an actuator for engaging and disengaging the shield with the portion of the workpiece.
49. (Previously amended): An apparatus as in claim 48 in which the actuator comprises a movable shaft connected to the workpiece support.
50. (Previously amended): An apparatus as in claim 41 in which the workpiece support has a top surface, the top surface of the workpiece support is circular and the shield has an annular form.
51. (Currently amended): A workpiece deposition system for replaceably preventing deposition on a portion of ~~the~~ a workpiece comprising:
- a) a ~~deposition~~ chamber for depositing a film on ~~[[a]]~~ the workpiece;
 - b) a workpiece support positioned within the ~~deposition~~ chamber for supporting the workpiece;
 - c) a replaceable shield of comparable weight as the workpiece, the shield engaging a portion of the workpiece on the opposite side of the workpiece support and shielding the engaged portion of the workpiece during deposition thereof to prevent deposition on the engaged portion of the workpiece;
 - d) an actuator to move and engage and disengage the shield with the portion of the workpiece;
 - e) a shield restraint clamp for holding the shield against the portion of the workpiece; and
 - f) a cavity defined by the workpiece support, the workpiece, the shield and the shield restraint clamp, the cavity adapted to retain a non-reactive gas in the vicinity of the shielded portion of the workpiece;
- wherein the comparable weight of the replaceable shield and the workpiece allows replacement of the shield in the same way as the replacement of the workpiece~~[[,]].~~

52. (Previously amended): An apparatus as in claim 51 in which the shield restraint clamp stays close to the workpiece support so that the cavity retaining the non-reactive gas has no large leak when the shield is engaged with the workpiece.
53. (Previously amended): An apparatus as in claim 51 in which the workpiece is a semiconductor wafer, and the cavity retains the non-reactive in the vicinity of the circumferencial edge of the semiconductor wafer.
54. (Previously amended): An apparatus as in claim 51 further comprising a shield restraint press for pressing on the shield restraint clamp so that the shield is pressing against the portion of the workpiece.
55. (Previously amended): An apparatus as in claim 54 in which the shield restraint press employs a spring action for pressing on the shield restraint clamp.
56. (Previously amended): An apparatus as in claim 51 further comprising a shield support for supporting the shield so that the shield and the workpiece are spaced apart when the shield is disengaged from the workpiece.
57. (Previously amended): An apparatus as in claim 56 further comprising shield aligner connected to the shield and the shield support for aligning the shield with the shield support.
58. (Previously amended): An apparatus as in claim 51 further comprising a shield restraint support for supporting the shield restraint clamp so that the shield and the shield restraint clamp are spaced apart when the shield is disengaged from the workpiece.
59. (Previously amended): An apparatus as in claim 51 in which the actuator comprises a movable shaft connected to the workpiece support.